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## ARTICLE

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## Highly Sensitive and Ultrafast Graphene Nanoribbons/CsPbBr<sub>3</sub> Quantum Dots Phototransistor with Enhanced Vertically Metal Oxide Heterostructures

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## **Supporting information**



Fig.S1 (a)AFM image of GNR surface morphology (scale bar: 300 nm). (b) The height information of profile 1 and 2 in GNR surface and profile of GNR/QDs hybrids. (c) AFM image of GNR/QDs hybrids' surface morphology. (d) AFM image on top of GNR/QDs/IGZO surface to illustrate roughness of this film.







Fig.S3 (a) Top-view of simulated electric field distribution of GNR on  $SiO_2$  substrate. SEM images of the origin GNR with different gaps :100 nm (b), 500 nm (c) and 900 nm (d). (e) SEM image of this phototransistor. (f) Transfer characteristic curves for vertical phototransistors under dark and 512 nm incident lights with different gaps.



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Fig.S4 (a) Transfer character curves of GNR/QDs/IGZO transistor with 400 nm and 600 nm gaps under dark and 512 nm light's illumination. (b)SEM image of GNR film with 600 nm gaps. (c) SEM image of GNR film with 400 nm gaps.



Fig.S5 Responsivity of GNR/QDs/IGZO and GNR/QDs phototransistors versus different wavelengths.



Fig. S6 (a) Device's field effect mobility of phototransistors with different GNR gaps. (b) linear transfer characteristic curves for P-type planar phototransistor ( $V_{DS}$ =0.6 V) with different incident light wavelengths.



Fig. S7 Time-duration on/off measurement for vertical phototransistor with an ultrafast light signal (512 nm, 0.1 mW/cm<sup>2</sup> mean power density).



Fig. S8 The schematic for measuring the dynamic pulse signal and connecting method with the series variable resistance box (left). And the estimating method to obtain equivalent resistance by transformation of Thevinen law.